

IN THE CLAIMS:

Claim 1 (currently amended): Workpiece [(1)] with at least one functional face and a layer system [(4)] deposited by means of a CVD or PVD process on at least a portion of the functional face [(4)] as well as a structure pattern, which encompasses at least a portion of the layer system [(4)] and which is comprised of at least one three-dimensional microstructure [(5)] with structure depth **S**, wherein the three-dimensional microstructure [(5)] extends from the surface of the layer system [(4)] up into the workpiece, such that it is uncoated in a lower region of the microstructure [(5)], wherein at least the outermost layer of the layer system [(4)] comprises at least one carbon-containing slide layer, the ratio of the layer thickness **d** of the layer system [(4)] to the structure depth **S** being between 0.05 and 0.9, and the carbon-containing slide layer being at least one of an Me/C, MeC/C, a-C:H:Si:Me, SiC/C, a-C:H:Si, a-C:H/a-Si:O, WC/C, or DLC slide layer, where Me is selected from the group consisting of: Ti, Zr, Hf, V, Nb, Ta, Cr, Mo, W or Fe.

Claims 2-5 (canceled).

Claim 6 (currently amended): Workpiece as claimed in claim [(2)] 1, wherein the carbon-containing layer comprises a metallic adhesion layer and a carbon content increasing from the adhesion layer to the surface.

Claim 7 (canceled).

Claim 8 (previously presented): Workpiece as claimed in claim 1, wherein the layer system comprises at least one hard layer and at least one slide layer deposited thereon.

Claim 9 (previously presented): Workpiece as claimed in claim 1, wherein the layer thickness of the layer system is between 0.5-20 μm .

Claim 10 (previously presented): Workpiece as claimed in claim 1, wherein the structure pattern in plan view is comprised of a multiplicity of substantially spot-form cavities, which, in turn, are disposed circularly, elliptically, in the form of lines, in the form of polygons or as hexagonal or cubic spot pattern.

Claim 11 (previously presented): Workpiece as claimed in claim 10, wherein the cavities, in turn, in plan view have a circular, elliptical or polygonal shaping.

Claim 12 (previously presented): Workpiece as claimed in claim 1, wherein the structure pattern is formed of circular, elliptical, polygonal, straight or wave-form lines.

Claim 13 (previously presented): Workpiece as claimed in claim 1, wherein on the portion of the layer system, encompassed by the structure pattern, the degree of areal coverage is between 10-50% of the microstructured surface.

Claim 14 (previously presented): Workpiece as claimed in claim 1, wherein the cross section of the cavities (5) is substantially circular (5').

Claim 15 (previously presented): Workpiece as claimed in claim 1, wherein a tangential angle α between the surface horizontal and a decreasing structure slope is less than 15°.

Claim 16 (previously presented): Workpiece as claimed in claim 1, wherein the structure pattern of the layer system comprises circular structures (5) with a diameter measured on the surface of 5 to 350 μm and has a degree of areal coverage of 10 to 50%.

Claim 17 (currently amended): Workpiece as claimed in claim 1, wherein the workpiece is a sliding structural part with at least one functional face implemented as a slide face.

Claim 18 (currently amended): Workpiece as claimed in claim 1, wherein the workpiece is a working tool with at least one functional face implemented as a slide face.

Claim 19 (currently amended): Method for the production of a workpiece with at least one functional face, at least on a portion of the functional face first a layer system is deposited by means of a CVD or PVD process and subsequently microstructured in one or several structuring steps, characterized in that the structuring steps are selected such

that the layer system as well as also the workpiece surface are microstructured, at least the outermost layer of the layer system (4) comprising at least one carbon-containing slide layer, the ratio of the layer thickness d of the layer system (4) to the structure depth S being between 0.05 and 0.9, and the carbon-containing slide layer being at least one of an Me/C, MeC/C, a-C:H:Si:Me SiC/C, a-C:H:Si, a-C:H/a-Si:O, WC/C, or DLC slide layer, where Me is selected from the group consisting of Ti, Zr, Hf, V, Nb, Ta, Cr, Mo, W or Fe.

Claims 20-21 (canceled).

Claim 22 (previously presented): Method as claimed in claim 19, wherein the at least one structuring step is selected such that a degree of areal coverage of 10 to 50% is set.

Claim 23 (previously presented): Method as claimed in claim 19, wherein the at least one structuring step comprises a micromechanical step.

Claim 24 (previously presented): Method as claimed in claim 19, wherein the at least one structuring step comprises plasma etching, chemical etching or electrochemical etching.

Claim 25 (previously presented): Method as claimed in claim 19, wherein the at least one structuring step comprises the application of an etch-resistant lacquer layer with

a two-dimensional structure pattern on the surface of the layer system or of the workpiece.

Claim 26 (previously presented): Method as claimed in claim 19, wherein the deposition of the layer system takes place by means of a combined PVD/CVD process.

Claim 27 (canceled).

Claim 28 (previously presented): Method as claimed in claim 19, wherein the layer thickness of the layer system is set between 0.5-20 μm .

Claim 29 (canceled).

Claim 30 (currently amended): Workpiece as claimed in claim 1, wherein the ratio of the layer thickness **d** of the layer system (4) to the structure depth **S** is between 0.1 and 0.6.

Claim 31 (currently amended): Workpiece as claimed in claim 1, wherein the at least one carbon-containing slide layer is selected from the group consisting of a layer of: SiC/C, a-C:H:Si, a-C:H:Si:Me, an a-C:H/a-Si:O, DLC, Me/C, MeC/C, and WC/C; the ratio of the layer thickness **d** of the layer system (4) to the structure depth **S** is between 0.1 and 0.6.

Claim 32 (currently amended): Workpiece as claimed in claim [[5]] 1, wherein the carbon-containing slide layer comprises at least one of the metals W or Cr.

Claim 33 (currently amended): Workpiece as claimed in claim 9, wherein the layer thickness of the layer system is between ~~between~~ 1-10 μm .

Claim 34 (previously presented): Workpiece as claimed in claim 13, wherein on the portion of the layer system, encompassed by the structure pattern, the degree of areal coverage is between 15-35%, of the microstructured surface.

Claim 35 (previously presented): Workpiece as claimed in claim 1, wherein the cross section of the cavities is substantially conical (5", 5''').

Claim 36 (previously presented): Workpiece as claimed in claim 1, wherein a tangential angle α between the surface horizontal and a decreasing structure slope is less than 10°.

Claim 37 (previously presented): Workpiece as claimed in claim 1, wherein the structure pattern of the layer system comprises circular structures (5) with a diameter measured on the surface of 80 to 250 μm , and has a degree of areal coverage of 15 to 40%.

Claim 38 (previously presented): Workpiece as claimed in claim 1, wherein the workpiece is a structural part with at least one functional face implemented as a slide face of at least one of a: friction bearing, slide seal, piston ring, bucket tappet, rocker arm, and crankshaft.

Claim 39 (previously presented): Workpiece as claimed in claim 1, wherein the workpiece is a tool with at least one functional face implemented as a contact face of a cutting tool.

Claim 40 (previously presented): Workpiece as claimed in claim 1, wherein the workpiece is a tool with at least one functional face implemented as an extrusion face of a forming tool.

Claim 41 (previously presented): Method as claimed in claim 19, wherein the at least one structuring step is selected such that the ratio of layer thickness **d** of the layer system (4) to the structure depth **S** is between 0.1 and 0.6.

Claim 42 (canceled).

Claim 43 (previously presented): Method as claimed in claim 19, wherein the at least one structuring step is selected such that a degree of areal coverage of between 15 to 40% is set.

Claim 44 (previously presented): Method as claimed in claim 19, wherein the at least one structuring step comprises a micromechanical step including working with a laser beam.

Claim 45 (canceled).

Claim 46 (currently amended): Method as claimed in claim 28, wherein the layer thickness of the layer system is set between ~~between~~ 1-10 μm .